IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Shiva Prakash

Title:

Atomic Force Microscopy Measurements Of Contact Resistance And Current-

Dependent Stiction

Serial No.

New – Divisional of Serial No. 10/202,439 filed 07/23/2002

Filing Date:

Herewith

Prior Art Unit:

2856

Prior Examiner

R. Raevis

Atty Docket:

061450/0304605 (FID-101-D1)

MAIL STOP: Patent Applications Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Express Mail Label No. EV 342 415 381 US

Date of Deposit: July 3, 2003

I hereby certify that this correspondence and the documents referred to as attached hereto are being deposited with the United States Postal Service on the above date in an envelope marked as "Express Mail Post Office to Addressee,", addressed to MAIL STOP Patent Applications, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 2/313-1450.

Kathleen M. Smith

INFORMATION DISCLOSURE STATEMENT

Applicant submits herewith patents, publications or other information of which Applicant is aware which are believed to be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR 1.56.

The filing of this information disclosure statement shall not be construed as a representation that a search has been made (37 CFR 1.97(g)), nor as an admission that the information cited is, or is considered to be, material to patentability, nor an admission that no other material information exists. The filing of this information disclosure statement shall not be construed as an admission against interest in any manner. Notice of January 9, 1992, 1135 O.G. 13-25, at 25.

The references cited herein were cited in the parent application Serial No. 10/202,439 filed July 23, 2002, and therefore copies are not included.

Respectfully submitted

PILLSBURY WINTHROP LLP

Ву

David A. Jakopin 🌠 🖋 No. 32,99

1600 Tysons Boulevard McLean, VA 22102 Talanhama Na. 650 222

Telephone No. 650-233-4500

INFORMATION DISCLOSURE CITATION PTO-1449				Atty Docket: 061450/0304605 FID-101-D1		Serial No. to be assigned		
F 10-1449				Applicant: S. Prakash				
Submitted: July 3, 2003				Filing Date: Herewith		Prior Group Art Unit: 2856		
-		U.S.	PATENT	APPLICATIONS				1.5
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME		CLASS	SUBCLASS	FILING	DATE
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EXAMINER'S INITIALS	PATENT NO.				CLASS		110113	1811011
							Yes	No
	OTHER DOC	UMENTS (Incl	uding Au	ıthor, Title, Date, Pe	rtinent Page	es, Etc.)		100
	De Wolf, et al. "Late	ral and vertical d	lopant prof	iling in semiconductors	by atomic force	e microscopy us	ing	- 100 C
conducting tops" (J. Vac. Sci. Tech. A 13(3), May/June 1995, pp. 1699-1704								
								
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EXAMINER				DATE CONSIDERED				

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.